

Inventor: Brenda D. Kraus et al.

Title: Atomic Layer Deposition Methods of Forming Conductive Metal Nitride Comprising Layers

Assignee: Micron Technology, Inc.

INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the cited art are included. No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 8-18-03

Attorney: 

Mark S. Matkin
Reg. No. 32,268

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2310		SERIAL NO. Unknown	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT: Brenda D. Kraus et al.			
				FILING DATE Filed Herewith		GROUP Unknown	
U.S. PATENT DOCUMENTS							
*Examiner's Initials		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	10/133,947		Vaartstra			04/25/2002
	AB						
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	AI						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
	AJ						
	AK						
	AL						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AM		Baghurst et al., <i>Microwave syntheses for superconducting ceramics</i> , 332 NATURE 11 (March 24, 1988).				
	AN		Kuo et al., <i>Microwave-assisted chemical vapor deposition process for synthesizing carbon nanotubes</i> ,				
			J. VAC. SCI. TECHNOL., Vol. 19, No. 3, pp. 1030-1033 (May/June 2001).				
	AO						
EXAMINER		DATE CONSIDERED					
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